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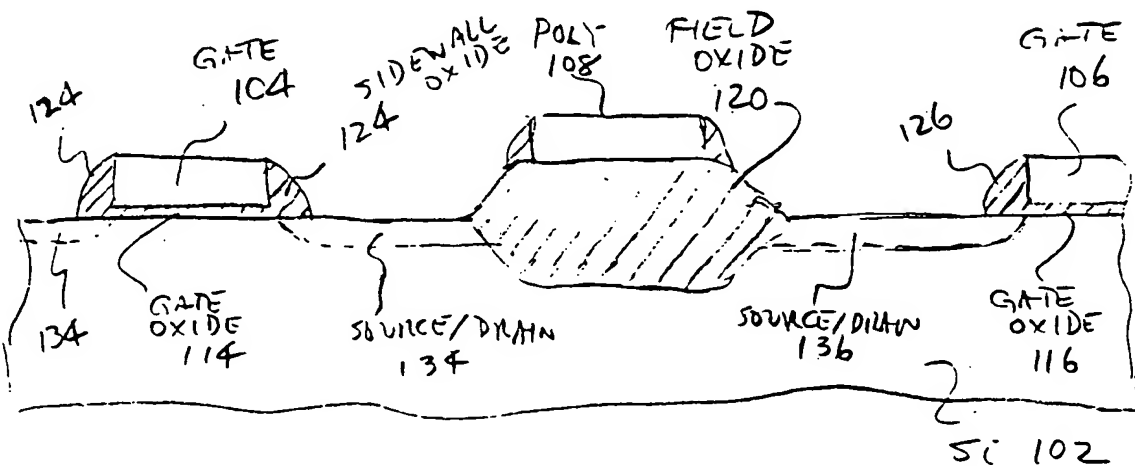


Fig. 1a (PRIOR ART)

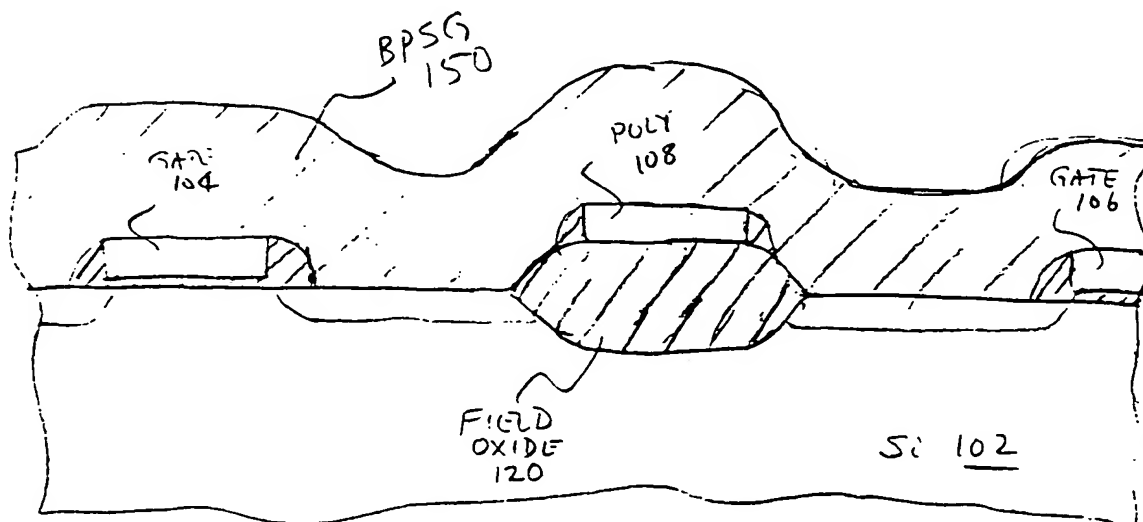


Fig. 1b (PRIOR ART)

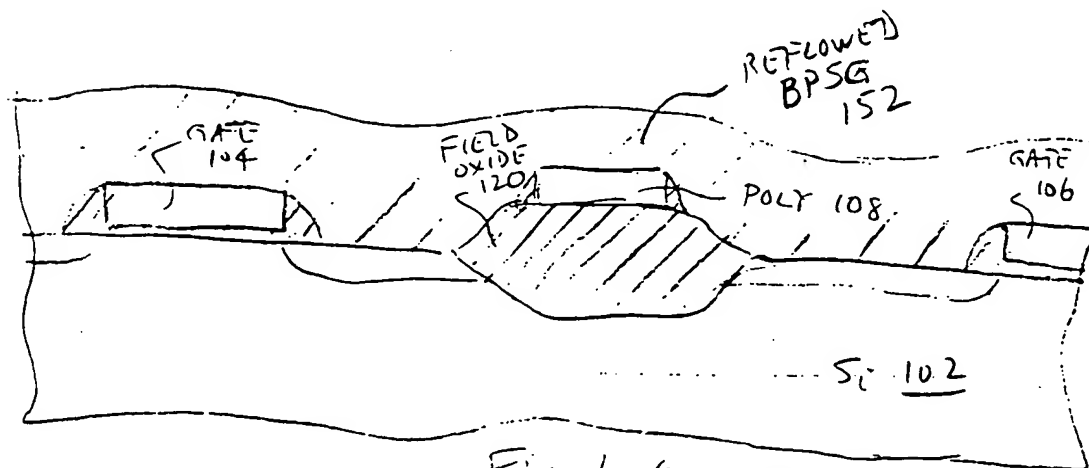


Fig. 1c (PRIOR ART)

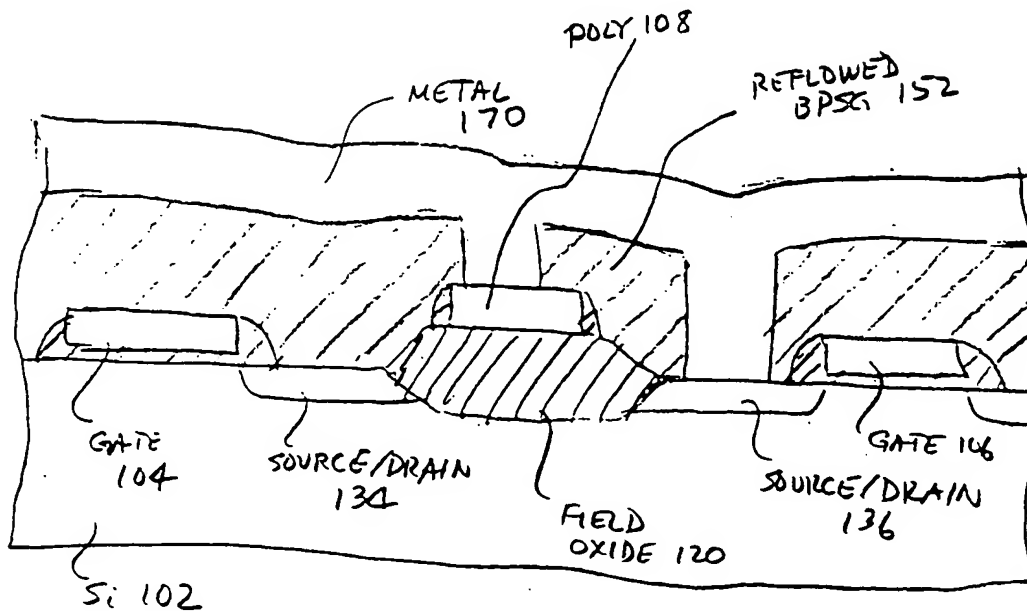


Fig. 1d (PRIOR ART)

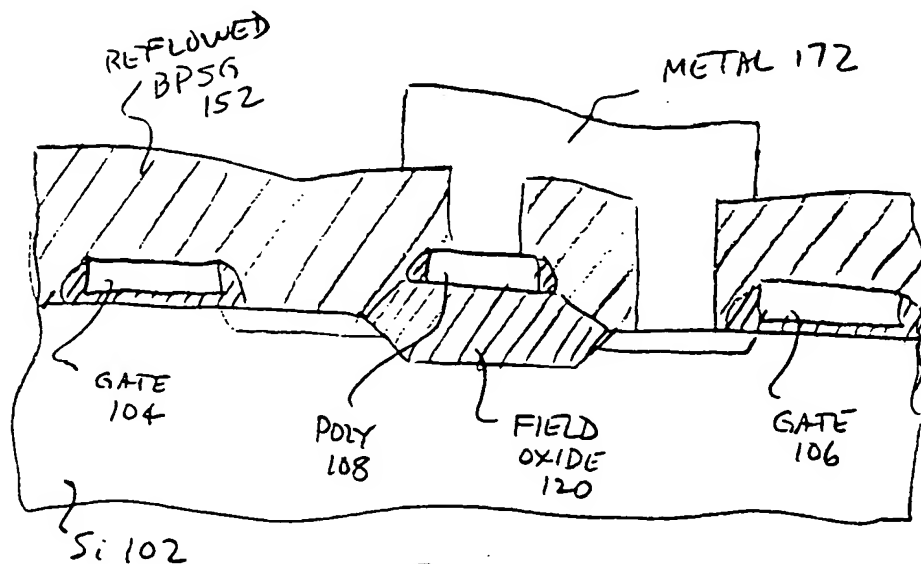


Fig. 1e (PRIOR ART)

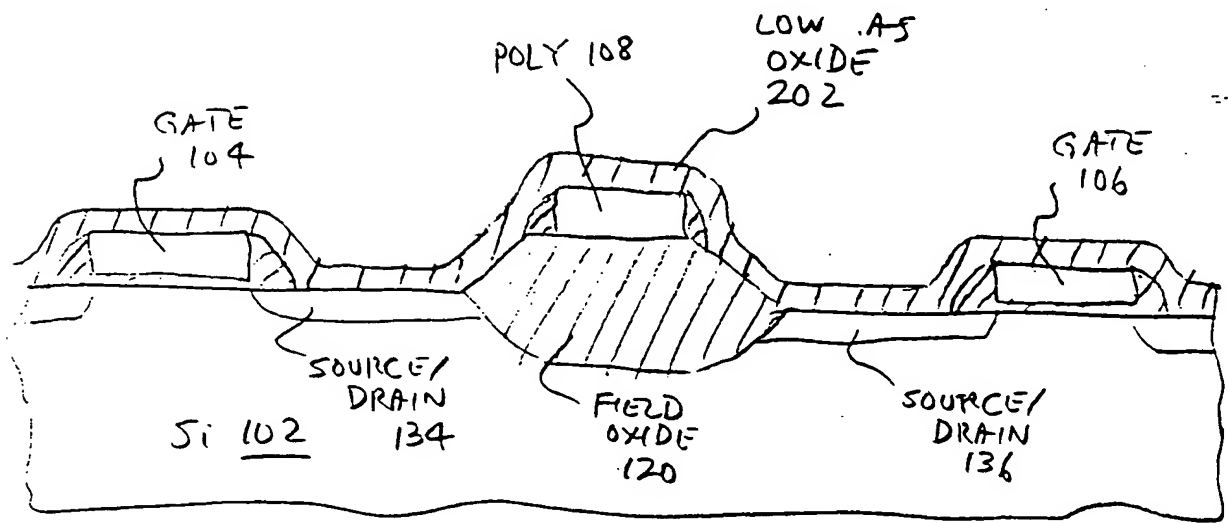


Fig. 2a

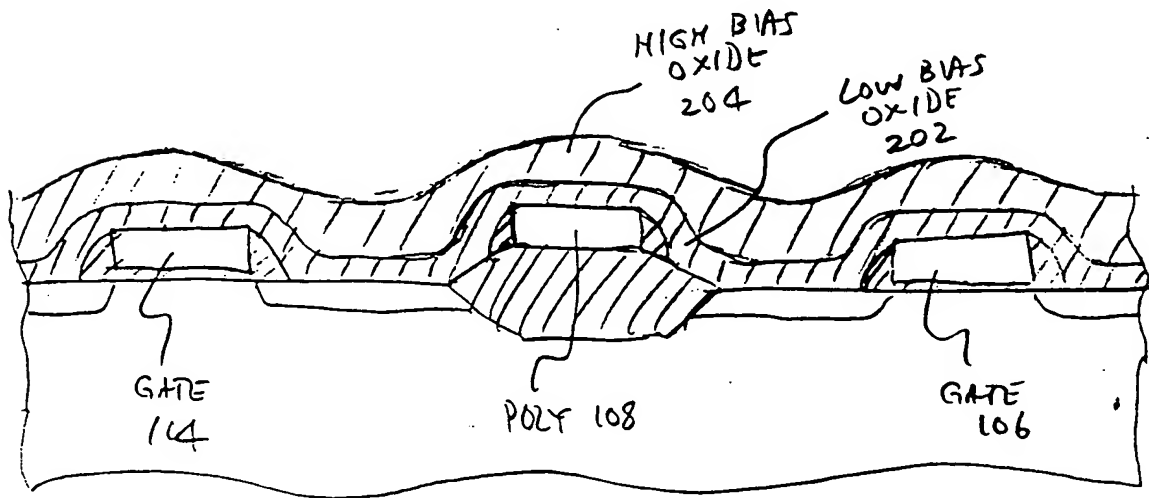


Fig. 2b

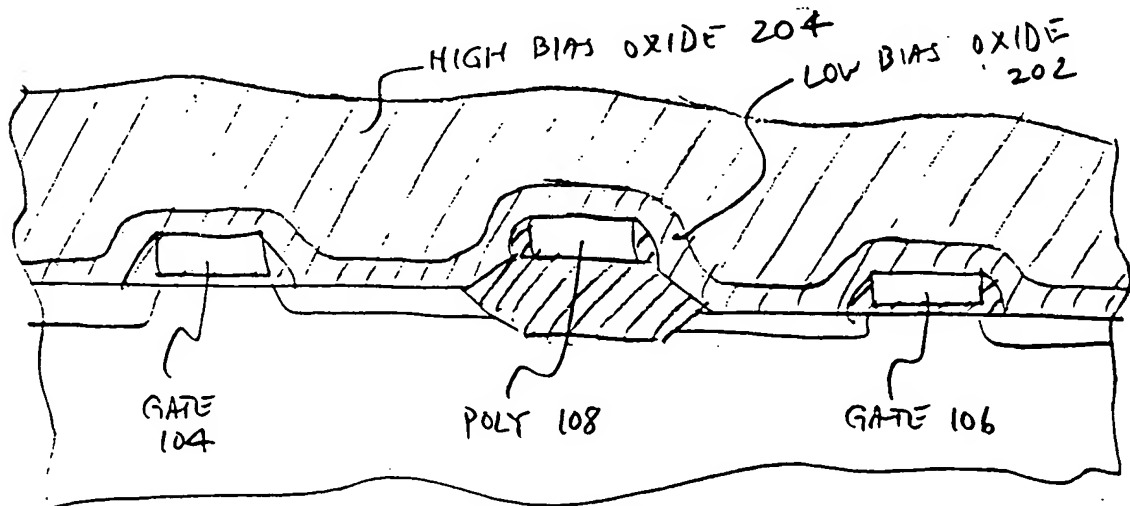
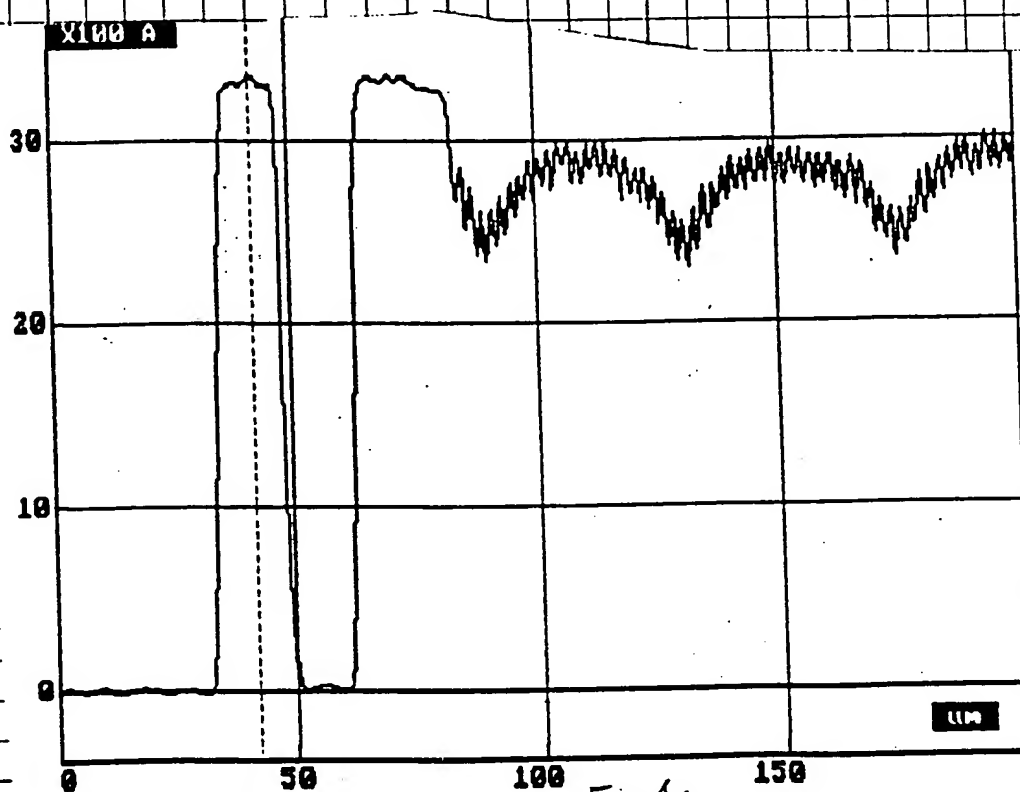
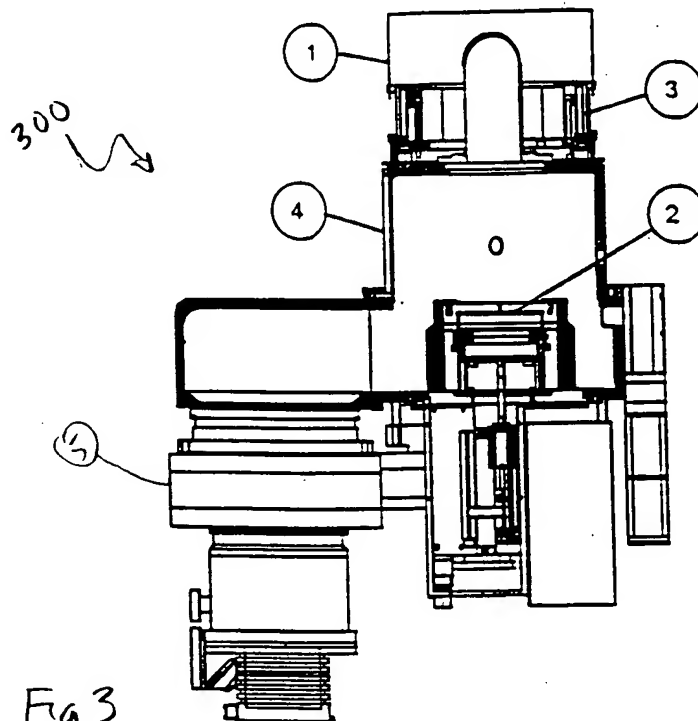


Fig. 2c



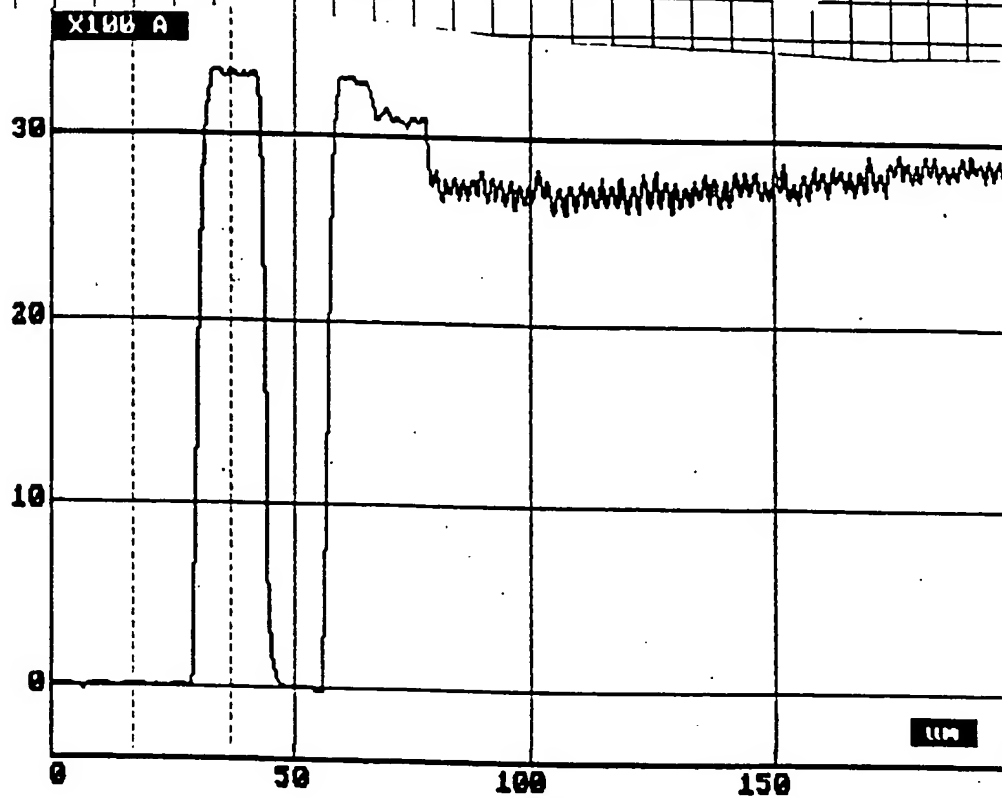


Fig. 4b

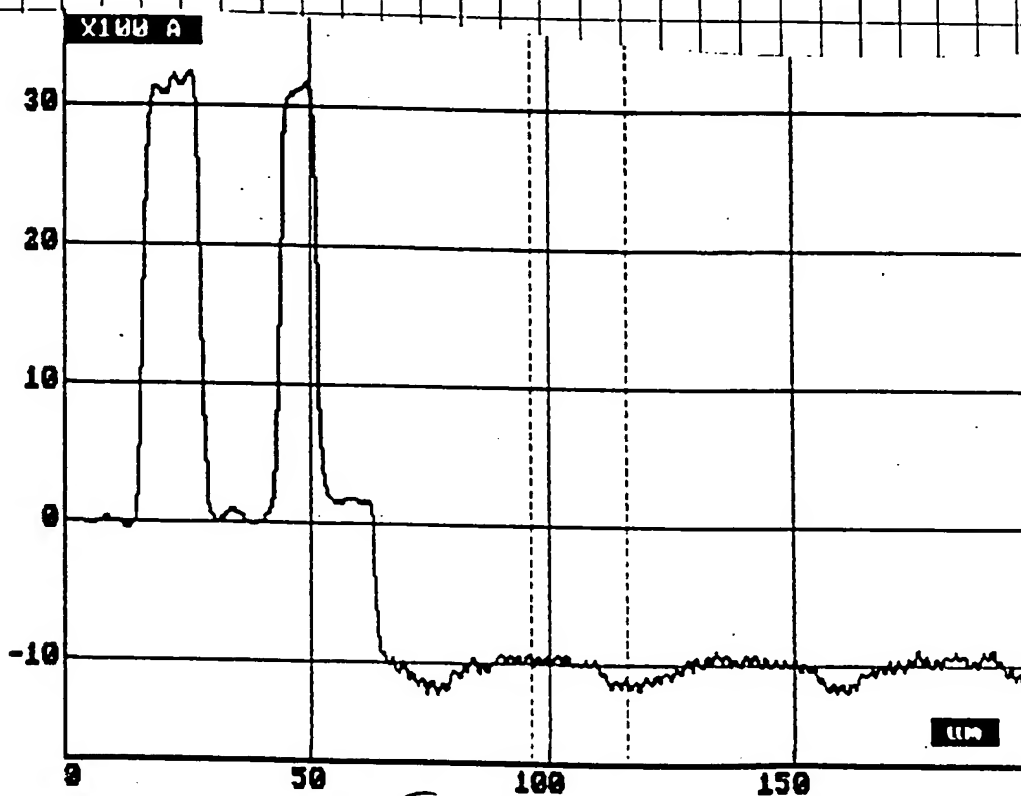


Fig. 4c



Fig. 4

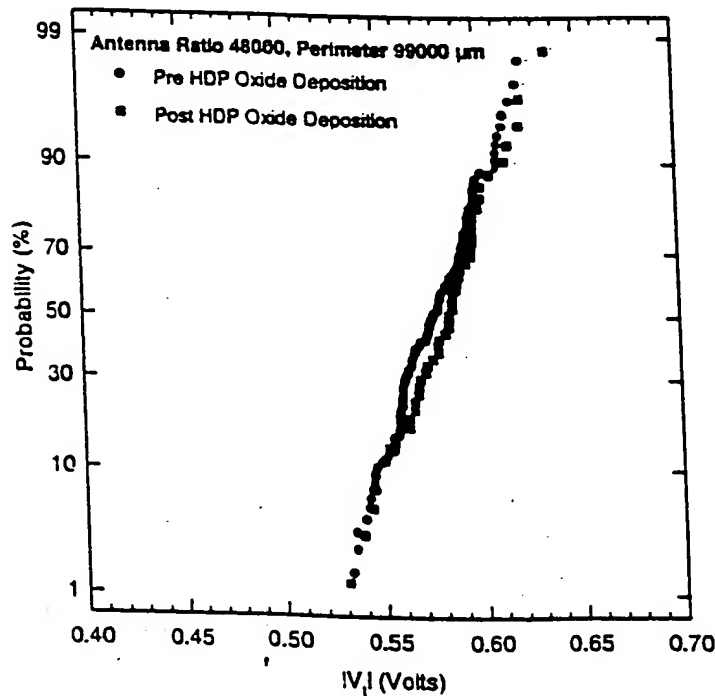


Fig. 5

Comparison of  $V_t$  distributions for PMOS transistors pre and post HDP-CVD oxide deposition for plasma damage evaluation

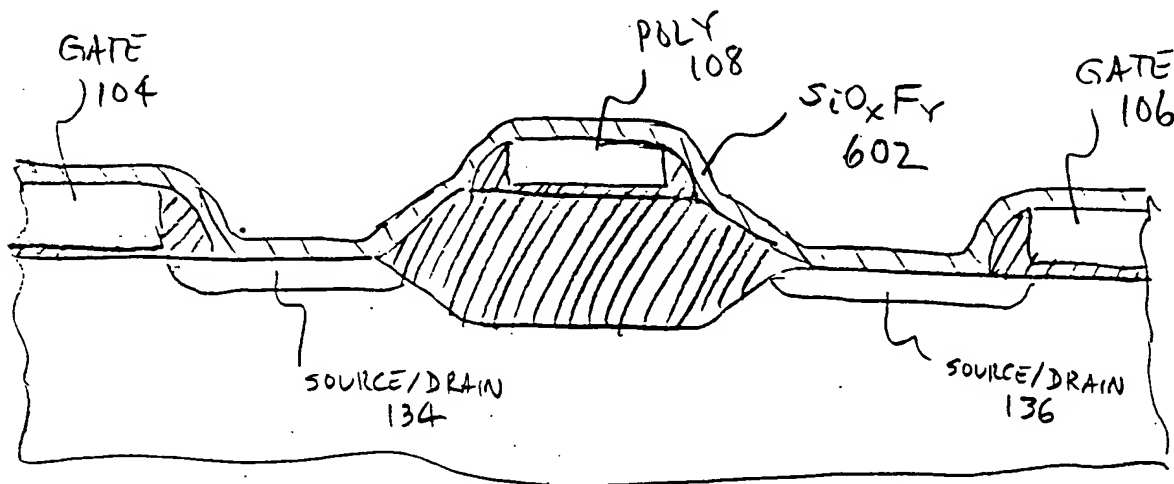


Fig. 6a

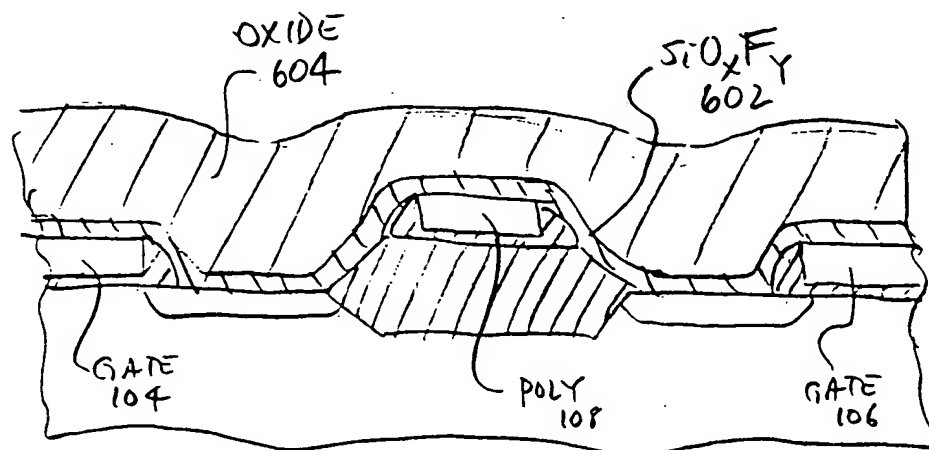


Fig. 6b